

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**  
(Case No. 213.007-US)

APR 25 2005

In the Application of: **YE ET AL.**Serial No: **10/815,573**Filed: **APRIL 1, 2004**Title: **SYSTEM AND METHOD OF LITHOGRAPHY  
SIMULATION**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Group Art Unit: **1756**

Before Examiner:

I hereby certify that this correspondence  
is being facsimile transmitted to the  
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Office, Fax No. (703) 872-9306 on  
April 25, 2005  
Date

Michiko Sites  
(name of person signing certificate)

Michiko Sites  
Signature

**STATEMENT OF RELATED APPLICATION**

Dear Sir:

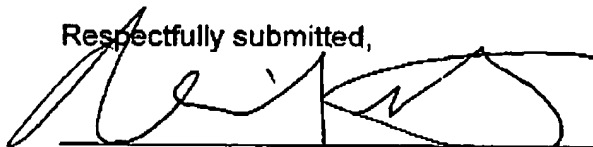
The above-referenced application is also related to the following application:

1. "System and Method of Lithography Simulation", Serial No. 11/084,484,  
filed March 18, 2005 (still pending).

Notably, this Statement of Related Application supplements the Statement of  
Related Applications filed on February 3, 2005.

Respectfully submitted,

Date: April 25, 2005



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